



# Diffusion of oxygen molecules in fluorine-doped amorphous SiO<sub>2</sub>

Koichi Kajihara<sup>a,b,\*</sup>, Taisuke Miura<sup>c</sup>, Hayato Kamioka<sup>d</sup>, Masahiro Hirano<sup>a,f</sup>,  
Linards Skuja<sup>a,e</sup>, Hideo Hosono<sup>a,f</sup>

<sup>a</sup> Transparent Electro-Active Materials Project, ERATO-SORST, Japan Science and Technology Agency, in Frontier Research Center, S2-13, Tokyo Institute of Technology, 4259 Nagatsuta, Midori-ku, Yokohama 226-8503, Japan

<sup>b</sup> Department of Applied Chemistry, Graduate School of Urban Environmental Sciences, Tokyo Metropolitan University, 1-1 Minami-Osawa, Hachioji 192-0397, Japan

<sup>c</sup> Research & Development Division, OMRON Laserfront Inc., 1120 Shimokuzawa, Sagami-hara 229-1198, Japan

<sup>d</sup> Graduate School of Pure and Applied Sciences, University of Tsukuba, 1-1-1 Tennodai, Tsukuba 305-8571, Japan

<sup>e</sup> Institute of Solid State Physics, University of Latvia, Kengaraga iela 8, LV1063 Riga, Latvia

<sup>f</sup> Materials and Structures Laboratory & Frontier Research Center, Tokyo Institute of Technology, 4259 Nagatsuta, Midori-ku, Yokohama 226-8503, Japan

## ARTICLE INFO

### Article history:

Received 30 June 2009

Received in revised form 9 December 2009

Accepted 4 January 2010

### Keywords:

SiO<sub>2</sub> glass  
Diffusion  
Interstitial O<sub>2</sub>  
Photoluminescence  
Glass transition

## ABSTRACT

Effects of fluorine doping on the diffusion of interstitial oxygen molecules (O<sub>2</sub>) in amorphous SiO<sub>2</sub> (*a*-SiO<sub>2</sub>) were compared to those obtained from *a*-SiO<sub>2</sub> containing SiOH groups. Incorporation of moderate concentration ( $\sim 10^{19}$  cm<sup>-3</sup>) of SiF groups gives rise to minor changes in diffusion parameters between 800 and 1100 °C: only a slight decrease in solubility and an increase in the activation energy for diffusion can be detected. Incorporation of SiOH groups has similar weak effects on the solubility and activation energy for diffusion. These minor changes are most likely due to the enhancement of the flexibility of local Si–O network as a result of the dissociation of the network by SiOH and SiF groups. However, in contrast to the SiF doping, SiOH doping leads to a notable decrease in the diffusion coefficient. The heat of solution changes by  $\sim 0.1$ – $0.2$  eV at  $\sim 1000$  °C and it is attributed to the glass transition of *a*-SiO<sub>2</sub>.

© 2010 Elsevier B.V. All rights reserved.

## 1. Introduction

Amorphous SiO<sub>2</sub> (*a*-SiO<sub>2</sub>) is widely used as gate dielectric films for silicon microelectronic circuits, optical fibers for telecommunication, and optical components in excimer laser photolithography. Fluorine is one of the most important dopant for *a*-SiO<sub>2</sub> used as such devices, because moderate fluorine doping increases the radiation hardness of *a*-SiO<sub>2</sub> [1–4], suppresses the electrical breakdown of the gate dielectric films, and improves the optical transmittance near the absorption edge of *a*-SiO<sub>2</sub> located at  $h\nu \simeq 8$  eV [5]. These improvements are mainly due to the breaking up of Si–O network by Si–F bonds. It decreases the viscosity of *a*-SiO<sub>2</sub> [3] and enhances the structural relaxation [6,7], facilitating the removal of “strained” Si–O–Si bonds, which are considered to be a major source of point defects in *a*-SiO<sub>2</sub> [8–13]. Furthermore, Si–F bonds themselves are stronger than Si–O bonds that build the *a*-SiO<sub>2</sub> network and are hardly decomposed. Thus, radiation hardness of fluorine-doped *a*-SiO<sub>2</sub> is better than that of *a*-SiO<sub>2</sub> containing other network mod-

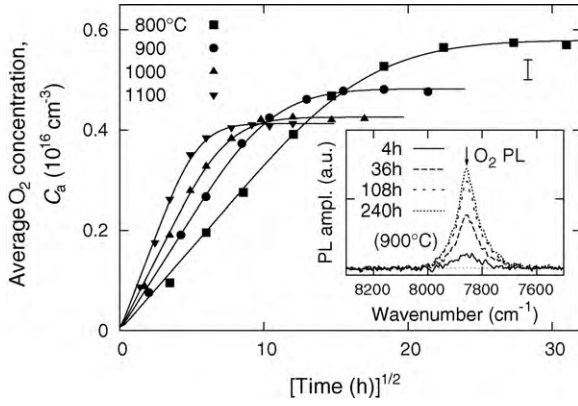
ifiers, such as SiOH and SiCl groups. Similarly to SiF groups they enhance the structural relaxation, however, they can be converted to point defects under radiation or electrical stress.

Oxygen molecules dissolved in interstices of Si–O network (interstitial O<sub>2</sub>) are the main mobile oxygen species in *a*-SiO<sub>2</sub> [14–16]. They play a key role in thermal oxidation of silicon [17] and radiation induced defect processes in *a*-SiO<sub>2</sub> [18]. Interstitial O<sub>2</sub> in *a*-SiO<sub>2</sub> are sensitively detected by their characteristic infrared photoluminescence at  $\sim 1273$  nm, attributed to the transition from the lower excited singlet state ( $a^1\Delta_g$ ) to the ground state ( $X^3\Sigma_g^-$ ) [19]. It is possible to detect as few as  $\sim 10^{14}$  cm<sup>-3</sup> interstitial O<sub>2</sub> when the upper excited singlet state ( $b^1\Sigma_g^+$ ) is populated using a continuous-wave laser light at a wavelength of 765 nm [20]. The sensitivity is sufficient to detect interstitial O<sub>2</sub> incorporated during thermal annealing in air [21], offering an easy and straightforward way to quantitatively study the thermal diffusion of interstitial O<sub>2</sub> in *a*-SiO<sub>2</sub> [22]. Furthermore, this PL method is precise enough to evaluate the variations of the solubility and diffusion coefficient of interstitial O<sub>2</sub> with the incorporation of  $\sim 10^{20}$  cm<sup>-3</sup> SiOH groups [23,18], which are the most common network modifiers in synthetic *a*-SiO<sub>2</sub>.

The purpose of the present study is to examine the influence of the incorporation of SiF groups on the diffusion of interstitial O<sub>2</sub> in *a*-SiO<sub>2</sub> and to compare it with that of SiOH groups.

\* Corresponding author at: Department of Applied Chemistry, Graduate School of Urban Environmental Sciences, Tokyo Metropolitan University, 1-1 Minami-Osawa, Hachioji 192-0397, Japan.

E-mail address: [kkaji@tmu.ac.jp](mailto:kkaji@tmu.ac.jp) (K. Kajihara).



**Fig. 1.** Variation of the thickness average of interstitial  $O_2$  concentration  $C_a$  with annealing time  $t$  for 1 mm-thick samples annealed in air at 800, 900, 1000, or 1100 °C. The error bar indicates the experimental uncertainty. The inset shows the PL band of interstitial  $O_2$  for samples annealed at 900 °C.

## 2. Experimental procedure

Fluorine-doped synthetic  $SiO_2$  glass containing  $\sim 1.4 \times 10^{19} \text{ cm}^{-3}$  of SiF groups and  $\sim 1.2 \times 10^{18} \text{ cm}^{-3}$  of SiOH groups was cut into specimens in the form of 7 mm  $\times$  10 mm  $\times$  1 mm, and the two largest faces were polished to an optical finish. They were thermally annealed in air at 800, 900, 1000, or 1100 °C to incorporate interstitial  $O_2$ . The PL band of interstitial  $O_2$  in the  $O_2$ -loaded samples was excited at 765 nm using an AlGaAs laser diode ( $\sim 1.5 \text{ W}$  at the sample position) and was measured using the detector part of a Fourier-transform Raman spectrometer (Model 960 Nicolet). The laser light was directed normal to the polished surface and the backscattered PL signal was recorded. The peak amplitude of the PL band is proportional to the thickness average of the concentration of interstitial  $O_2$ ,  $C_a$ , and the proportionality factor was determined using a reference sample with a known  $O_2$  concentration.

## 3. Results

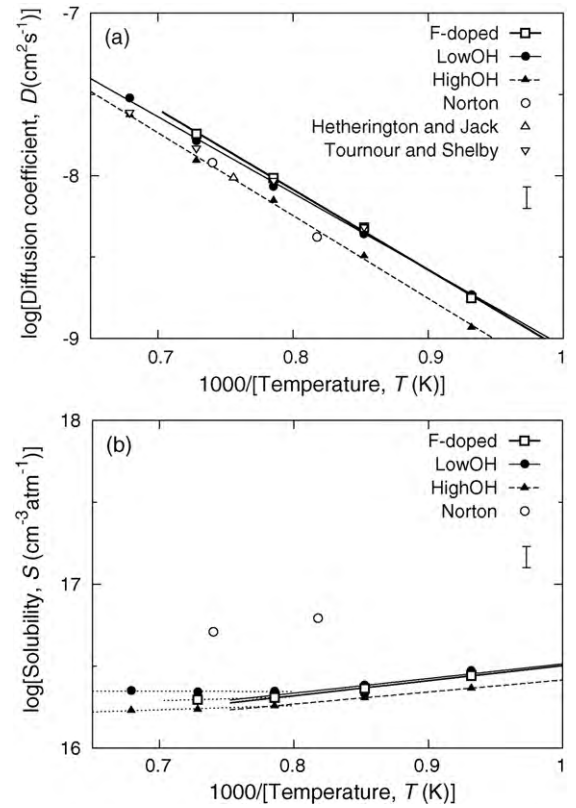
Fig. 1 shows the variation of  $C_a$  with annealing time  $t$  at 800, 900, 1000, or 1100 °C.  $C_a$  was proportional to  $t^{1/2}$  at small  $t$ , and saturated at a constant value at large  $t$ . This observation indicates that the dissolution of  $O_2$  from air is much faster than the following  $O_2$  diffusion in  $\alpha$ - $SiO_2$  [22] and is consistent with previous results [22,23]. Thus, the observed variation of  $C_a$  with  $t$  was simulated well by an equation describing the simplest one-dimensional diffusion in a parallel sheet of a thickness  $L$  [24],

$$\frac{C_a(t)}{C_0} = 1 - \frac{8}{\pi^2} \sum_{n=1}^{\infty} \frac{\exp[-D(2n-1)^2\pi^2 t/L^2]}{(2n-1)^2}, \quad (1)$$

using the diffusion coefficient  $D$  and the saturation concentration  $C_0$  as adjustable parameters. The best-fit theoretical curves are shown as solid lines in Fig. 1. The solubility  $S$  was calculated from the relation  $S = C_0/p_{O_2}$ , where  $p_{O_2}$  is the partial pressure of  $O_2$  in air at atmospheric pressure ( $p_{O_2} = 0.209 \text{ atm}$ ), provided that  $C_0$  is proportional to  $p_{O_2}$  at this pressure range [15,23].

The  $D$  and  $S$  values derived from the data shown in Fig. 1 are plotted in Fig. 2 and are referred to as “F-doped”. Both  $\log D$  and  $\log S$  were almost proportional to the reciprocal of the absolute temperature  $T$ , with slight deviations starting to appear above  $\sim 1000^\circ \text{C}$  in the  $S$  plot. Apart from the point at 1100 °C in the  $S$  plot, these data were fitted to the simple Arrhenius-type relations

$$D = D_0 \exp(-\Delta E_a/kT), \quad (2)$$



**Fig. 2.** Arrhenius plots of the diffusion coefficient (a) and solubility (b) of interstitial  $O_2$ . Data taken from Refs. [15,35,23,36] are also shown. The error bars indicate the experimental uncertainty for data obtained by our group (F-doped, LowOH, and HighOH). The dotted lines at  $T \geq 1000^\circ \text{C}$  in panel (b) correspond to linear fits drawn to guide the eye.

$$S = S_0 \exp(-\Delta H/kT), \quad (3)$$

to evaluate the activation energy for diffusion  $\Delta E_a$ , the heat of solution  $\Delta H$ , and the preexponential factors  $D_0$  and  $S_0$ .  $k$  in Eqs. (2) and (3) denotes the Boltzmann constant. The calculated parameters are listed in Table 1. The experimental uncertainties of  $\Delta E_a$  and  $D_0$  were larger for the F-doped sample than for the LowOH and HighOH samples reported previously [23,18], because the temperature range used for the fitting of the F-doped sample data was narrower.

## 4. Discussion

Fig. 2 also shows  $D$  and  $S$  values of interstitial  $O_2$  reported to date. The obtained  $\Delta E_a$ ,  $\Delta H$ ,  $D_0$ , and  $S_0$  values are listed in Table 1, along with the measurement method, sample type, and abbreviated name. Agreements among data are good for  $D$ ,  $\Delta E_a$ , and  $\Delta H$ . However, our  $S$  data are  $\sim 2.5$  times smaller than those reported in Ref. [15].

The LowOH sample is fluorine-free and contains SiOH groups in concentration comparable with that in the F-doped sample. In these two samples the behavior of diffusion of interstitial  $O_2$  is very similar, except for a subtly higher  $\Delta E_a$  and smaller  $S$  in the F-doped sample. This observation indicates that incorporation of  $\sim 10^{19} \text{ cm}^{-3}$  SiF groups does not significantly modify the diffusion of interstitial  $O_2$ .

The diffusion of molecular species in solids has been studied well for amorphous organic polymers, and these results may provide insight into the diffusion of molecular species in  $\alpha$ - $SiO_2$ . In amorphous organic polymers,  $\Delta H$  above the glass transition temperature ( $T_g$ ) is generally larger (i.e., smaller by absolute value since

Download English Version:

<https://daneshyari.com/en/article/1530173>

Download Persian Version:

<https://daneshyari.com/article/1530173>

[Daneshyari.com](https://daneshyari.com)